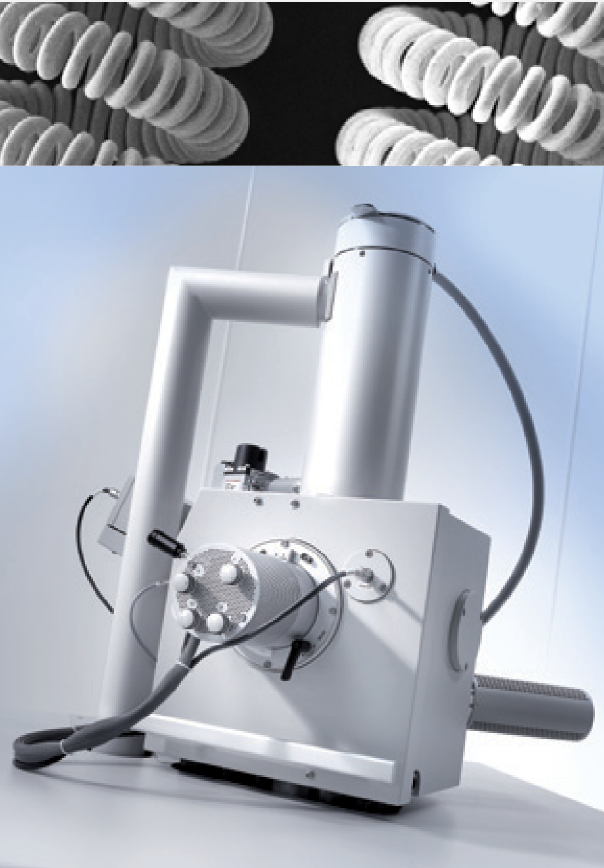
Product Overview



# Inspect™ S50

## Easy to use mainstream SEM enabling quick, accurate answers

Tailored for the mainstream need to investigate a wide variety of materials and characterize their structure and composition, the easy to use Inspect™ S50 provides flexibility and versatility to handle most research needs. The Inspect provides all the data: surface and compositional images can be combined with elemental analysis for determining material properties and elemental composition.

Today's research extends beyond simple metals and coated samples and the Inspect S50 can handle both conductive and non-conductive sample types. Characterization of traditional samples from metals, fractures and polished sections, to non-conductive soft materials is easy and fast, maximizing the time of research staff. The user interface is simple and easy to learn, yet flexible enough for the challenges. For example, standard navigation features include double-click stage movements and drag to zoom. SmartSCAN™ technology for smart scanning strategies makes it easier to reduce noise and provide better data. Designed by microscopists for microscopists, this instrument series is truly above and beyond being merely 'easy to use'.

Many features are available to help customize an Inspect S50 for particular characterization or research needs. Additional options, such as beam deceleration, bring low kV performance to a completely different level for a tungsten based SEM. Nav-Cam™ color image navigation and new detectors provide even greater flexibility to the Inspect S50.

Better data. More flexibility. Higher efficiency. The Inspect S50 enables quick and simple operation to get quick answers and delivers more value for the investment.

### Key benefits

- Easy to use, intuitive software makes highly effective operation possible for novice users
- Characterize conductive and non-conductive samples easily
- Minimize the amount of sample preparation: low vacuum enables charge free imaging and analysis of non-conductive specimens
- Increase analytical capabilities by enabling accurate EDS and EBSD analysis on conductive and non-conductive samples in high and low vacuum thanks to the patented through-the-lens pumping
- Stable high beam currents (up to 2 µA) enable fast, accurate analytical analysis
- Enable surface imaging with optional beam deceleration mode to get surface and compositional information from conductive samples